

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasunori HATAMURA, et al.

SERIAL NO: 10/549,283

GAU: 1716

FILED: June 21, 2006

EXAMINER: ZERVIGON, RUDY

FOR: METHOD AND APPARATUS FOR REDUCING SUBSTRATE BACKSIDE
DEPOSITION DURING PROCESSING
INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

Submitted herewith is a Chinese Office Action (English translation only) for the Examiner's consideration.
The reference cited therein was previously cited by the Examiner on April 29, 2009.

RELATED CASES

Attached is a list of applicant's pending application(s), published application(s) or issued patent(s) which may be related to the present application. In accordance with the waiver of 37 CFR 1.98 dated September 21, 2004, copies of the cited pending applications are not provided. Cited published and/or issued patents, if any, are listed on the attached PTO form 1449.

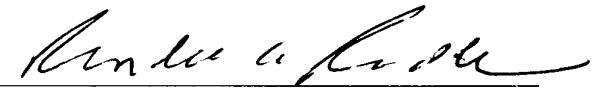
CERTIFICATION

Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application and, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

Respectfully submitted,

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